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L. Spruill

I hereby certify that this correspondence is being deposited with the United States Postal Service on the date set forth below as First Class Mail in an envelope addressed to: Box Amendment, Commissioner for Patents, Washington, D. C. 20231.

Date of Signature and Deposit: November 14, 2002

Fee OK

Adam J. Zinn  
Attorney of Record

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):

Richard D. Harris, et. al.

Serial No.:

09/967,157

Filed:

September 28, 2001

For:

Method for fabricating a microelectromechanical system (MEMS) device using a pre-patterned bridge

Group Art Unit:

2812

Docket No.:

110003.97630

TECHNOLOGY CENTER 2800  
REC'D  
NOV 22 2002

## AMENDMENT

Box Amendment  
Commissioner for Patents  
Washington, D. C. 20231

Dear Sir:

In response to the Office Action dated August 14, 2002, please amend the above-identified patent application as follows:

## IN THE CLAIMS:

The following revised claims should be substituted for the like numbered claims that were filed with the patent Application. Claims 15, 24, 33, 49, and 50 should be cancelled from the application. New claims 53-102 should be added to the application. A version of the claims with markings to show changes made is attached to the end of this document.

1. (Once Amended) A method of fabricating a MEMS structure, comprising the steps of:

- (a) providing a wafer having at least a first layer and a second layer;
- (b) removing a portion of the first layer through to the second layer to form a bridge member;
- (c) after step (b), attaching the wafer to the upper surface of a substrate

to form a composite structure having an internal void formed therein, wherein the

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